

# 2015 CCRF Training Program

## □ 2015 CCRF Training Program(Public Facilities)

- Period: from March to December, 2015
- Irregular programs also can be held by requests.

No.	Regular/ Irregular	Equipment	Title	date and time		Trainees (Persons)	Remarks
1	regular	3D Rapid Prototyping System	3D Rapid Prototyping System training for users	2015.08.28	10:00~15:00	10	
2	regular	AFM	AFM training for users	2015.03.27	10:00~15:00	5	
3	regular	Bio-AFM	Bio-AFM user training	2015.07	2 <sup>nd</sup> week	10	
4	regular	Bio-SEM	Bio-SEM user training	2015.06	4 <sup>th</sup> week	10	
5	regular	Bio-TEM	Bio-TEM user training	2015.06	2 <sup>nd</sup> week	15	
6	regular	Bio-TEM	Bio-TEM user training	2015.12	2 <sup>nd</sup> week	15	
7	regular	Calcium ratio imaging system	Calcium ratio imaging system user training	2015.09	2 <sup>nd</sup> week	15	
8	regular	Cluster Sputter	User operation training on Cluster Sputter	2015.04.02	10:00~14:00	5	
9	regular	Cluster Sputter	User operation training on Cluster Sputter	2015.10.07	10:00~14:00	5	
10	regular	COMSOL	COMSOL user training(First half)	2015.04.02		10	Theory and Practice
11	regular	COMSOL	COMSOL user training(Second half)	2015.10.02		10	Theory and Practice
12	regular	Dicing saw	Dicing saw self-user training	March, September schedule	14:00~18:00	10	
13	regular	EBL (Electron Beam Lithography)	Introduction of EBL	2015.04.28	14:00~18:00	10	Not including practice
14	regular	EBL (Electron Beam Lithography)	Introduction of EBL	2015.11.12	14:00~18:00	5	Not including practice
15	regular	Electrospray Ionization Time-of-Flight Spectrometer	ESI tof MS user training	2015.03	4 <sup>th</sup> week	10	
16	regular	RIEsystem, Metal Etching System, Cluster ICP Etcher, Deep RIE, PRasher, Xenon etcher	Etch equipment self-user training	April, October schedule	14:00~18:00	10	
17	regular	Automated High-speed Flow	FACS user training	2015.05	3 <sup>rd</sup> week	10	

No.	Regular/ Irregular	Equipment	Title	date and time		Trainees (Persons)	Remarks
		Cytometry Sorter System(FACS)					
18	regular	Automated High-speed Flow Cytometry Sorter System(FACS)	FACS user training	2015.11	3 <sup>rd</sup> week	10	
19	regular	FE-SEM & Sample preparation equipment	FE-SEM user training & Sample preparation equipment training	2015.04.21	10:00~16:00	15	Taehoon Cheon, Jiyoung Park
20	regular	FE-SEM & Sample preparation equipment	FE-SEM user training & Sample preparation equipment training	2015.09.22	10:00~16:00	15	Taehoon Cheon, Jiyoung Park
21	regular	FT-NMR	FT-NMR user training	2015.04.07	13:00~16:00	10	
22	regular	FT-NMR	FT-NMR user training	2015.09.08	13:00~16:00	10	
23	regular	High Precision Laser Cutting System for Nonmetallics	High Precision Laser Cutting System for Nonmetallics training for users	2015.10.30	10:00~15:00	10	
24	regular	High resolution live cell imaging system	High resolution live cell imaging system user training	2015.05	2 <sup>nd</sup> week	15	
25	regular	In vivo imaging system	In vivo imaging system user training	2015.04	1 <sup>st</sup> week	5	
26	regular	In-vivo micro-CT	In-vivo micro-CT	2015.11	4 <sup>th</sup> week	10	
27	regular	BioStation	Matrix screening system user training	2015.08	2 <sup>nd</sup> week	15	
28	regular	NIL (Nano-Imprinting Lithography)	Introduction of NIL	2015.10.02	14:00~17:00	10	Not including practice
29	regular	PALM	Photoactivated localization microscopy user training	2015.04	2 <sup>nd</sup> week	15	
30	regular	SR-SIM	Superresolution structured illumination microscopy user training	2015.04	2 <sup>nd</sup> week	15	
31	regular	Surface plasmon resonance system	Surface plasmon resonance system user training	2015.03.17	13:00~18:00	15	
32	regular	Surface plasmon resonance system	Surface plasmon resonance system user training	2015.03.18	10:00~18:00	15	
33	regular	LPCVD, furnace, Ellipsometer, Thickness measurement	Thin film equipment self-user training	April, October schedule	14:00~18:00	10	

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34	regular	UV-Vis-NIR	UV-Vis-NIR user training	2015.04.21	13:00~15:00	10	
35	regular	UV-Vis-NIR	UV-Vis-NIR user training	2015.09.22	13:00~15:00	10	
36	regular	XRD	XRD user training	2015.04.14	13:00~16:00	10	
37	regular	XRD	XRD user training	2015.09.15	13:00~16:00	10	
38	regular	Nano Probe Manipulator	SEM Nano Manipulation I	March 4 <sup>th</sup> week	13:00~16:00	5	Introduction & Practice
39	regular	Nano Probe Manipulator	SEM Nano Manipulation II	June 4 <sup>th</sup> week	13:00~16:00	5	Introduction & Practice
40	regular	Atom Probe Microscopy	APM Introduction & Theory I	May	4 <sup>th</sup> week	5	Introduction & Theory
41	regular	Atom Probe Microscopy	APM Introduction & Theory II	August	3 <sup>rd</sup> week	5	Introduction & Theory
42	regular	Animal Care Lab.	Animal care and User guide	2015.03	10:00~12:00	25	
43	regular	Animal Care Lab.	Animal care and User guide	2015.04	10:00~12:00	25	
44	regular	Animal Care Lab.	Animal care and User guide	2015.05	10:00~12:00	25	
45	regular	Animal Care Lab.	Animal care and User guide	2015.06	10:00~12:00	25	
46	regular	Animal Care Lab.	Animal care and User guide	2015.07	10:00~12:00	25	
47	regular	Animal Care Lab.	Animal care and User guide	2015.08	10:00~12:00	25	
48	regular	Animal Care Lab.	Animal care and User guide	2015.09	10:00~12:00	25	
49	regular	Animal Care Lab.	Animal care and User guide	2015.10	10:00~12:00	25	
50	regular	Animal Care Lab.	Animal care and User guide	2015.11	10:00~12:00	25	
51	regular	Animal Care Lab.	Animal care and User guide	2015.12	10:00~12:00	25	
52	regular	PR Track, Mask	Notice of training for	2015.04.23	10:00~14:00	5	

No.	Regular/ Irregular	Equipment	Title	date and time		Trainees (Persons)	Remarks
		Aligner, inspection microscope, laser writer	users on lithography technology				
53	regular	PR Track, Mask Aligner, inspection microscope, laser writer	Notice of training for users on lithography technology	2015.10.21	10:00~14:00	5	
54	regular	Device Cleanroom	Clean room access guide training I	2015.03.11	13:00~18:00	15	
55	regular	Device Cleanroom	Clean room access guide training II	2015.03.12	13:00~18:00	15	
56	regular	Device Cleanroom	Clean room access guide training III	2015.09.09	13:00~18:00	15	
57	regular	Device Cleanroom	Clean room access guide training IV	2015.09.10	13:00~18:00	15	